

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2851

(

00862.022151.

**PATENT APPLICATION** 

		# 11
In re Application of:	)	5/23/
Masaya OGURA et al.	: Examiner: H. Nguyen )	A
Application No.: 09/811,419	: Group Art Unit: 2851	
Filed: March 20, 2001	: )	
For: EXPOSURE APPARATUS, METHOD OF MANUFACTURING SEMICONDUCTOR DEVICES AND PLANT THEREFOR		RECE MAY 2
Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450		ECEIVED IAY 21 2003 LOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

AMENDMENT AFTER FINAL REJECTION WITH PETITION FOR EXTENSION OF TIME

05/20/2003 MDAMTE1 00000103 09811419

01 FC:1252

410.00 OP

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated December 17, 2002, for two months from March 17, 2003, up to and including Monday, May 19, 2003. A check in the amount of \$410.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, or credit any overpayment, to Deposit Account 06-1205.

Void date: 05/20/2003 IDMITES 05/45093 OFFC: 1252

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4047.00 OP

Please amend the above-identified application as follows in response to the Official Action dated December 17, 2002:

## **INTRODUCTORY COMMENTS**

This Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4, 2003, and entitled "Amendments in a Revised Format Now Permitted."